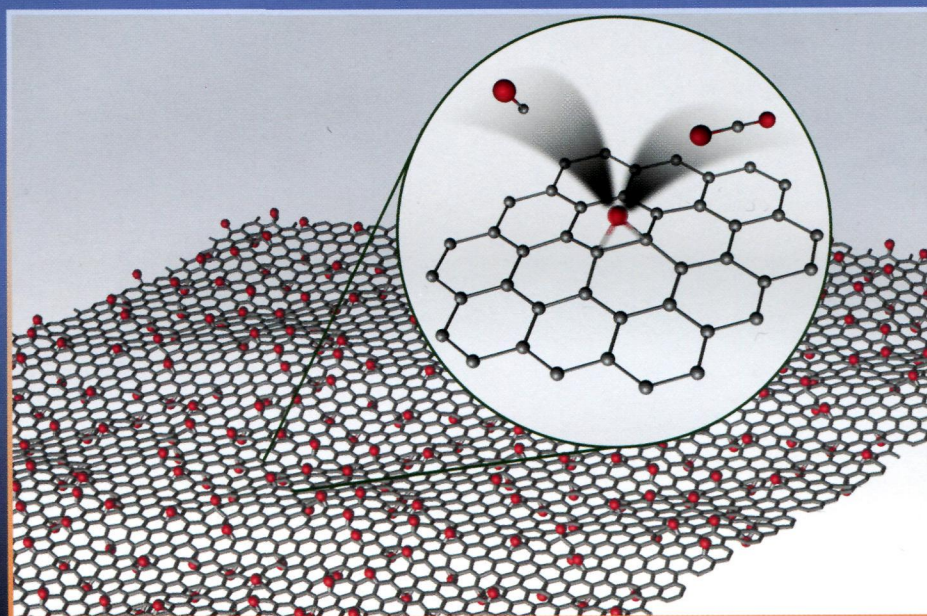


# JVSTA

Journal of Vacuum Science & Technology A | 2nd Series | Volume 31, Number 4 | July/August 2013

## Vacuum, Surfaces, and Films



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### Review Article:

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Present status and future opportunities

-by Han Zhou and Stacey F. Bent



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**On The Cover:** *B. Narayanan, S. L. Weeks, B. N. Jariwala, B. Macco, J.-W. Weber, S. J. Rathi, M. C. M. van de Sanden, P. Sutter, S. Agarwal, C. V. Ciobanu, JVST A, 31(4), p. 040601-1 (2013). Cover shows, schematically, a carbon monoxide molecule reducing the epoxide from an oxidized graphene sheet. The process is barrierless for all prevalent oxygen-containing functional groups present on the carbon basal plane, and the reduction mechanisms are described in the article for these functional groups.*